

IN THE CLAIMS

Please amend claim 12 as follows:

12. (Amended) A specimen inspection system, comprising:
a light energy source;
a multiple element offset fly lens arrangement for receiving energy from said energy source and selectively passing the light energy received;
a lensing arrangement for measuring and canceling topographical variations during inspection;
a pinhole mask for filtering light energy received from said lensing arrangement; and
a time delay and integration charge coupled device for receiving light energy from the pinhole mask.

Please amend claim 19 as follows:

19. (Amended) The specimen inspection system of claim 15, wherein said fly lens array comprises a plurality of offset individual lenses.

Please amend claim 24 as follows:

24. (Amended) A system for inspecting a semiconductor wafer specimen, comprising:
illumination means for generating light energy;
multiple element passing means for selectively filtering and passing energy received from said illumination means;
lensing means for imparting light energy onto said semiconductor wafer specimen;
masking means for further selectively filtering and passing energy received from said lensing means; and
a time delay integration charge coupled device for receiving light energy from said masking means;
wherein said multiple element passing means comprises an offset fly lens arrangement.

Please amend claim 32 as follows:

32. (Amended) A method for inspecting a specimen, comprising:
generating light energy;
selectively filtering and passing energy received from said light energy generating
using a multiple element offset fly lens arrangement;
imparting light energy from the multiple element arrangement onto said
specimen;
further selectively filtering and passing energy reflected from said specimen; and
performing a time delay and integration sensing function on light energy received
from said further selectively filtering and passing.